

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<p>Applicant: Toshihide TSUBATA et al.</p> <p>Application No.: 10/595,640</p> <p>Confirmation No.: 3891</p> <p>Filing or 371(c) Date: May 2, 2006</p> <p>Title: TRANSISTOR AND CVD APPARATUS USED TO DEPOSIT GATE INSULATING FILM THEREOF</p>	<p>Art Unit: 2818</p> <p>Examiner: E. Taylor</p>
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AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated September 15, 2008, please amend the above-identified application as follows:

- ☐ **Amendments to the Specification** begin on page of this paper.
- ☒ **Amendments to the Claims** begin on page **2** of this paper.
- ☐ **Amendments to the Drawings** begin on page of this paper and include an attached replacement sheet. An **Appendix** including the amended drawing figures is attached following page of this paper.
- ☒ **Remarks/Arguments** begin on page **4** of this paper.

Please note, if a box is not checked, then no corresponding amendment is being made.